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Notice of Allowability	Application No.	Applicant(s)	
	10/710,880	HSU ET AL.	
	Examiner	Art Unit	
	Igwe U. Anya	2891	
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.			
1. X This communication is responsive to <u>Paer filed 23 February 2006</u> .			
2. The allowed claim(s) is/are <u>1-26</u> .			
3.			
Paper No./Mail Date  Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of			
each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).  6. DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.			
<ul> <li>Attachment(s)</li> <li>1. ☑ Notice of References Cited (PTO-892)</li> <li>2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948)</li> <li>3. ☐ Information Disclosure Statements (PTO-1449 or PTO/SB/08 Paper No./Mail Date</li></ul>	5. Notice of Informal Page 1. Interview Summary Paper No./Mail Date 8), Examiner's Amendm 8. Examiner's Stateme 9. Other	(PTO-413), e nent/Comment	·

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## Allowable Subject Matter

The following is an examiner's statement of reasons for allowance. Applicant's
 claims 1 – 26 are allowable, because prior art does not render obvious:

providing a support wafer having a planar exposed surface comprising of oxide and substrate regions;

bonding an Integrated Circuit wafer to the surface of the support wafer only at the oxide regions; and

cutting through the IC wafer, wherein during the cutting process the IC wafer separates from the supporting wafer at the non-oxide regions of the support wafer .

2. Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

## Remarks

3. The examiner has reviewed prior art in light of applicant's comments and amendment. Prior art considered, but not used in the rejection include Ohara et al. (US Patent 5668033).

## Contact Information

4. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Igwe U. Anya whose telephone number is (571) 272-1887. The examiner can normally be reached on M - F 8:30am - 5:00pm.

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5. If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, William B. Baumeister can be reached on (571) 272-1722. The fax phone number for the organization where this application or proceeding is assigned is 571-

273-8300.

6. Information regarding the status of an application may be obtained from the

Patent Application Information Retrieval (PAIR) system. Status information for

published applications may be obtained from either Private PAIR or Public PAIR.

Status information for unpublished applications is available through Private PAIR only.

For more information about the PAIR system, see http://pair-direct.uspto.gov. Should

you have questions on access to the Private PAIR system, contact the Electronic

Business Center (EBC) at 866-217-9197 (toll-free).

Igwe U. Anya Examiner

Art Unit 2891

March 3, 2006

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